

Excitation Processes

• Electronic transitions due to the change of the principal quantum numbers of the electronic states ($\rightarrow visible$).

spin and nuclear spin. Electronic fine structure transitions due to the coupling of electron

electron. the nuclear magnetic moment with the magnetic Electronic hyperfine structure transitions due to the interaction of field of the

and vibrational (change in vibrational energy) transitions*, requiring dipole moment and moment of inertia I (\rightarrow near-far-IR). Molecular transitions such as <u>rotational</u> (change in angular momentum)

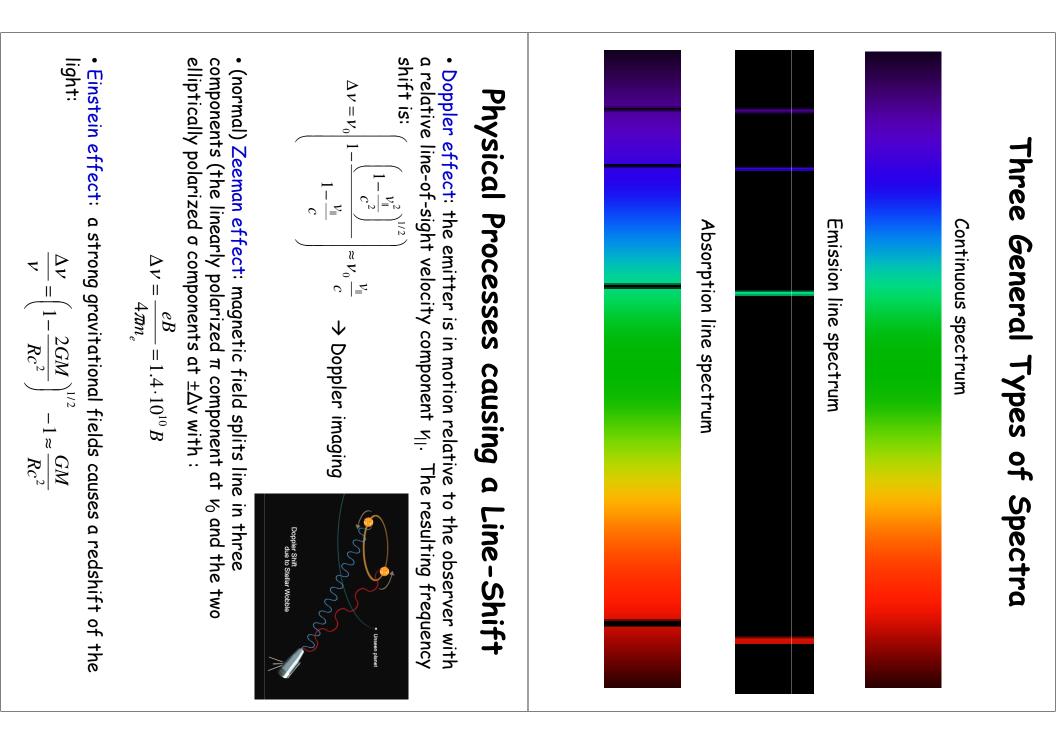
annihilation ($\rightarrow MeV range$) Nuclear lines due to nuclear excititations or electron-positror

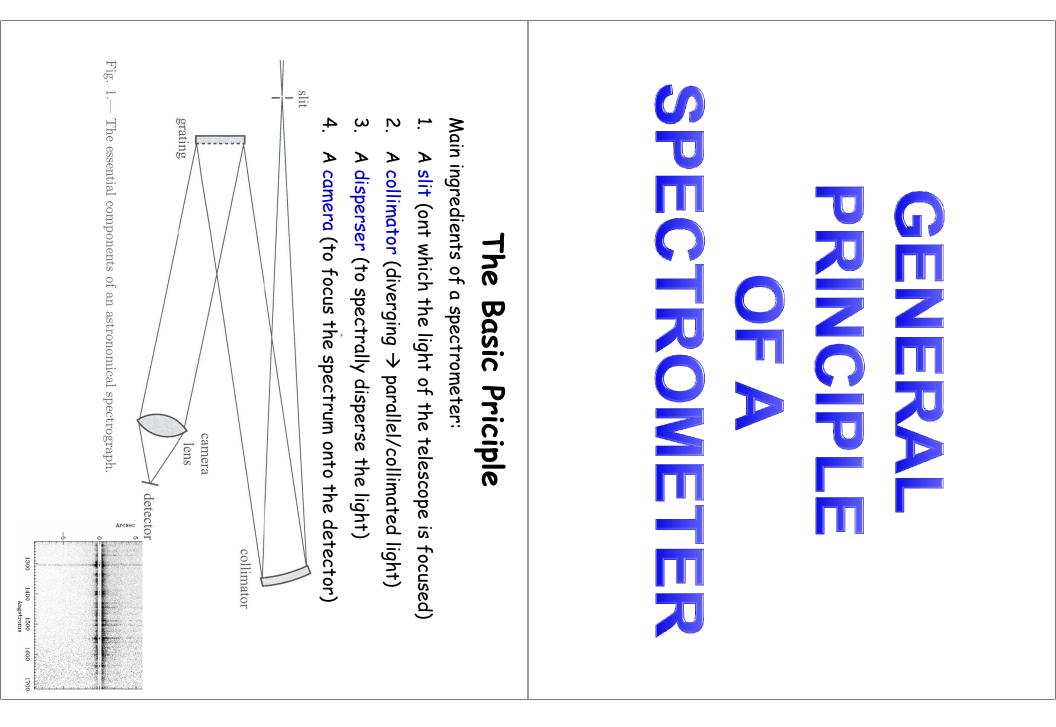
IR). Transitions in solids (ices) due to vibrations → phonons (→ near-far-

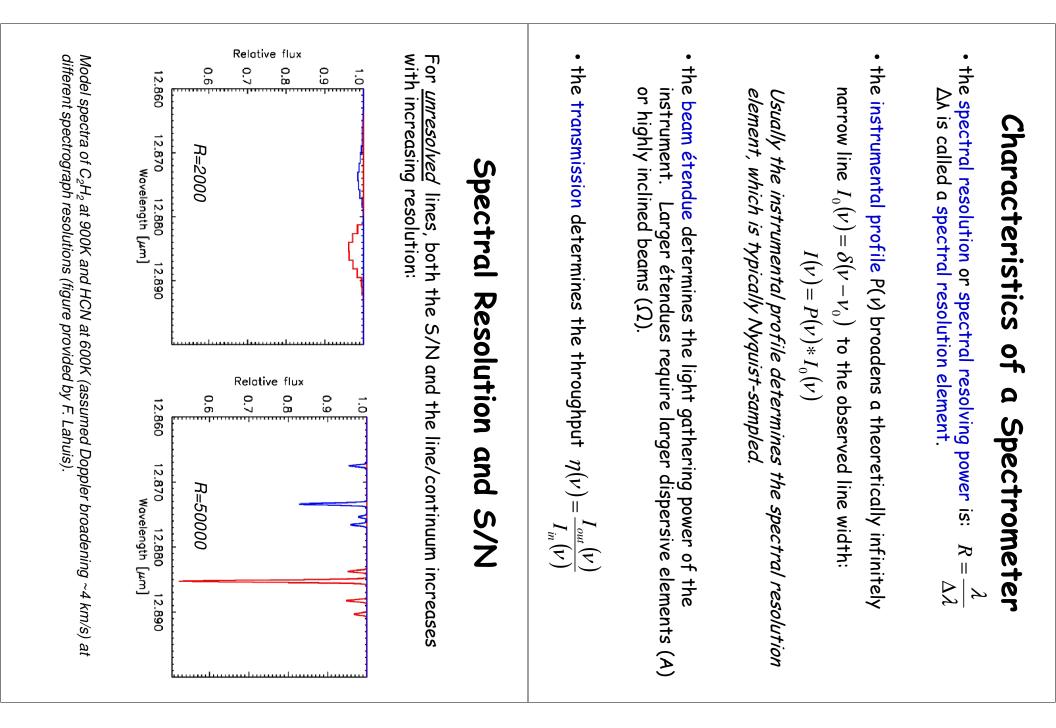
* rotational transitions are generally weaker and often coupled to vibrational transitions \rightarrow vibrational transitions split further: complex structure of vibrational-rotational transitions.

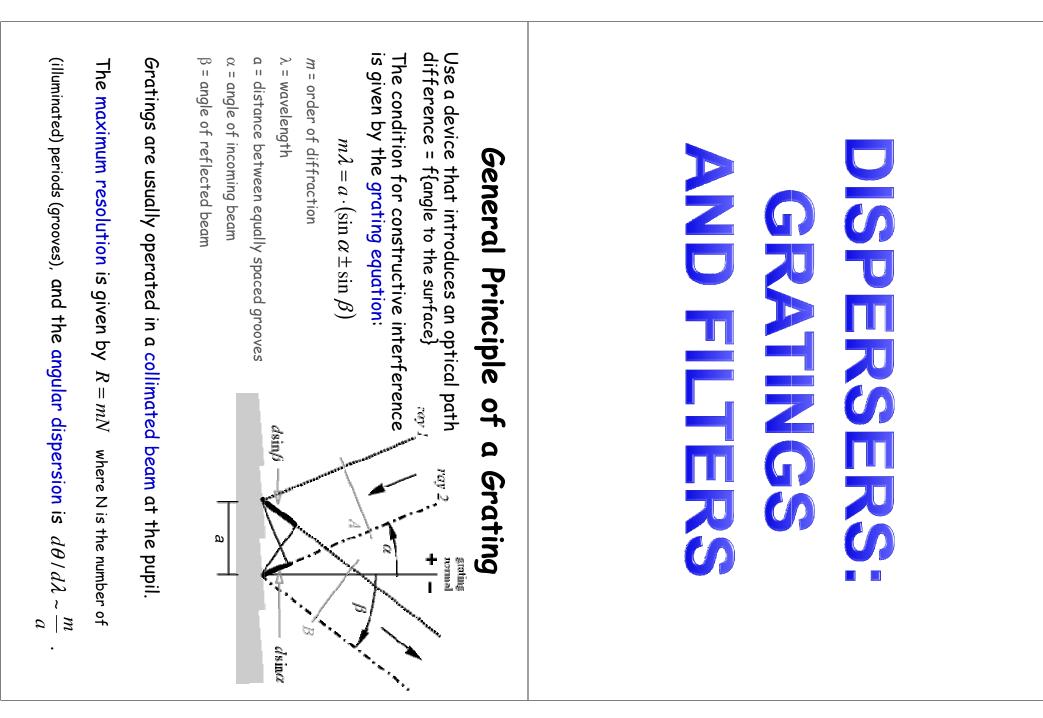
Transition	Energy [eV]	Spectral Region	Example
Hyperfine structure	10^{-5}	Radiofrequencies	21 cm hydrogen line
Spin-orbit coupling	10^{-5}	Radiofrequencies	1 667 MHz transitions of OH molecule
Molecular rotation	10^{-2} -10 ⁻⁴	Millimetre and infrared	1–0 transition of CO molecule at 2.6 mm
Molecular rotation- vibration	$1 - 10^{-1}$	Infrared	${ m H}_2$ lines near 2 $\mu{ m m}$
Atomic fine structure	$1 - 10^{-3}$	Infrared	Ne II line at 12.8 μm
Electronic transitions of atoms, molecules and ions	10^{-2} -10	Ultraviolet, visible, infrared	Lyman, Balmer series, etc. of H; resonance lines of C I, He I; K, L shell electron lines (Fe XV, O VI)
Nuclear transitions	$> 10^{4}$	X- and γ-rays	$^{12}\mathrm{C}$ line at 15.11 keV
Annihilations	$\gtrsim 10^4$	γ-rays	Positronium line at 511 keV

Excitation Processes **Energy Ranges**







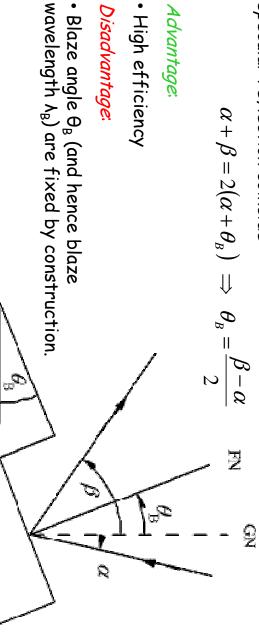


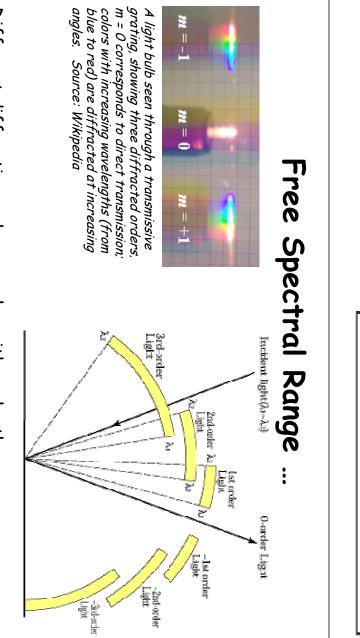
Blaze Angle

Generally, the energy of the beam diffracted by a periodic structure is uniformly distributed over the different orders *m*.

If we observe only one arbitrary order this is very inefficient

For blazed gratings the directions of constructive interference and specular reflection coincide:





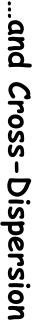
Different diffraction orders overlap with each other:

 $m\lambda = a(\sin \alpha + \sin \beta) = (m+1)\lambda^{2}$

$$\Delta \lambda_{free} = \lambda - \lambda' = rac{\lambda'}{m}$$

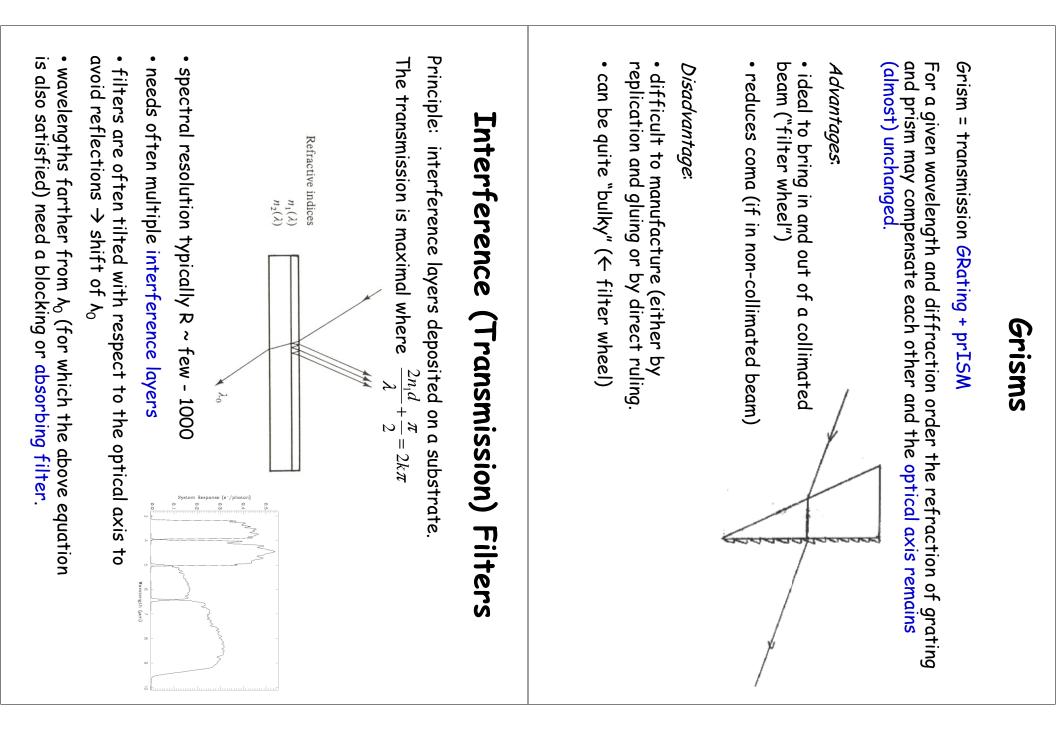
order that does not overlap the same range in an adjacent order.

The free spectral range is the largest wavelength range for a given



groove density, *or* use large groove periods (a >> A) and a large angle of optical element will be needed: If $a = \beta = \Theta \rightarrow$ Littrow configuration incidence, and operate at a very high order of diffraction (m \sim 50). A low-dispersion prism/grating with a dispersion direction perpendicular to that of the high-dispersion grating To get high dispersion $d heta/d\lambda\simrac{m}{-}$ To spatially separate the orders and avoid overlap, an additional Pre-disperser Echelle grating ordern Order nx, Q II Order nx2 δ Echelle П Detector Φ L Ð n a Gratings one could *either* increase the cross dispersion high dispersion

In Littrow configuration the grating equation becomes: $m\lambda_{_B} = 2a\sin\Theta$



Fabry-Perot Etalon

Two parallel plates (Fabry-Perot etalon) of high reflectivity *r* and transmission *t* = 1-*r*.

The transmission is:

$$I = I_0 \left(\frac{r}{1-r}\right)^2 \left[1 + \frac{4r}{(1-r)^2} \sin^2(2\pi dk \cos i)\right]^{-1}$$

and has transmission peaks where $k = \frac{m}{2d}$

 R_0

R'

Here, *m* is the order of the interferometer, d is the separation of the plates, and $\Delta k = 1/2d$ the free spectral range.

The performance of a Fabry-Perot is characterized by:

1. The finesse
$$F = \frac{\pi \sqrt{r}}{1-r}$$
 ,

2. The resolution
$$R = \frac{k}{\Lambda k} = mF$$
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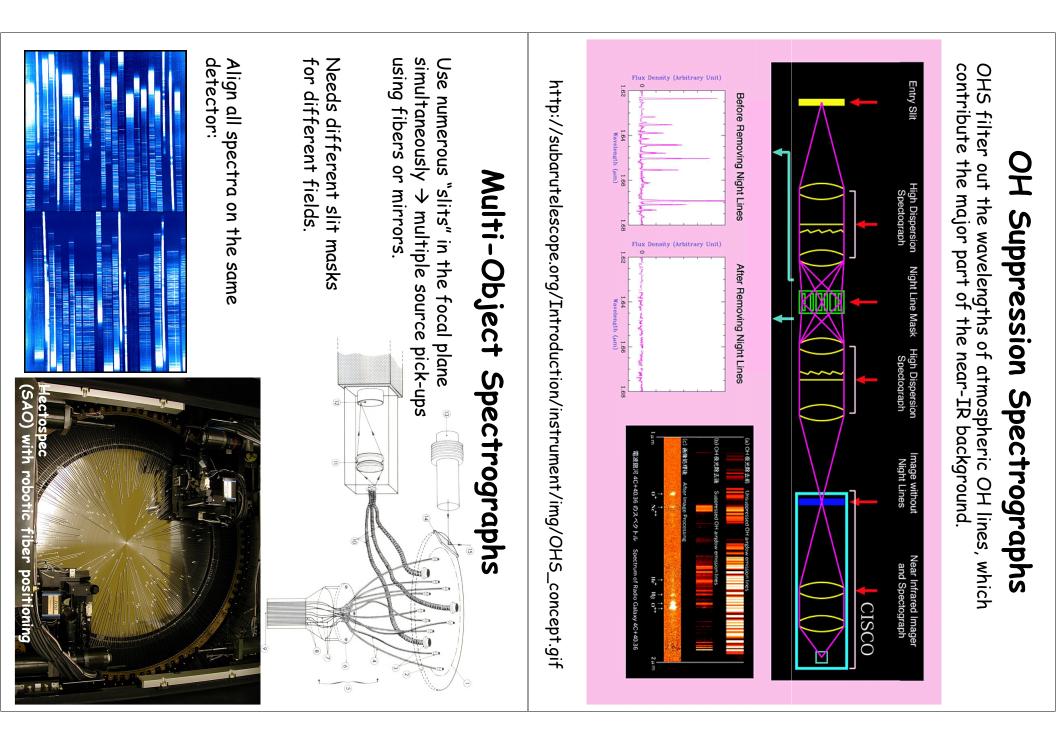
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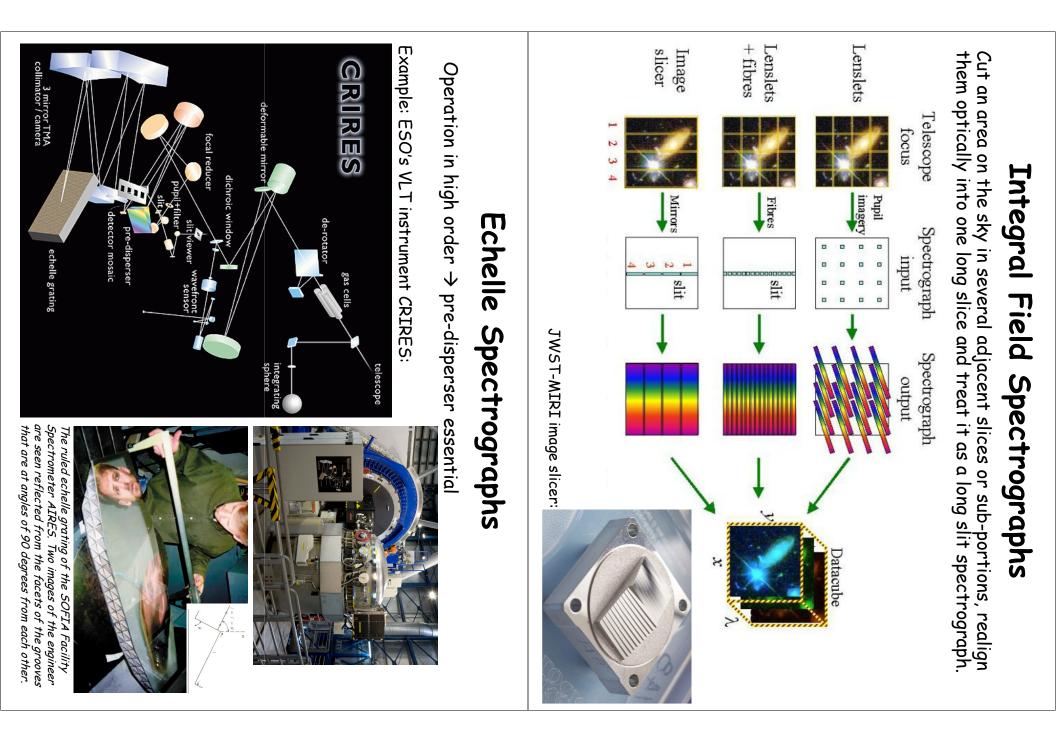
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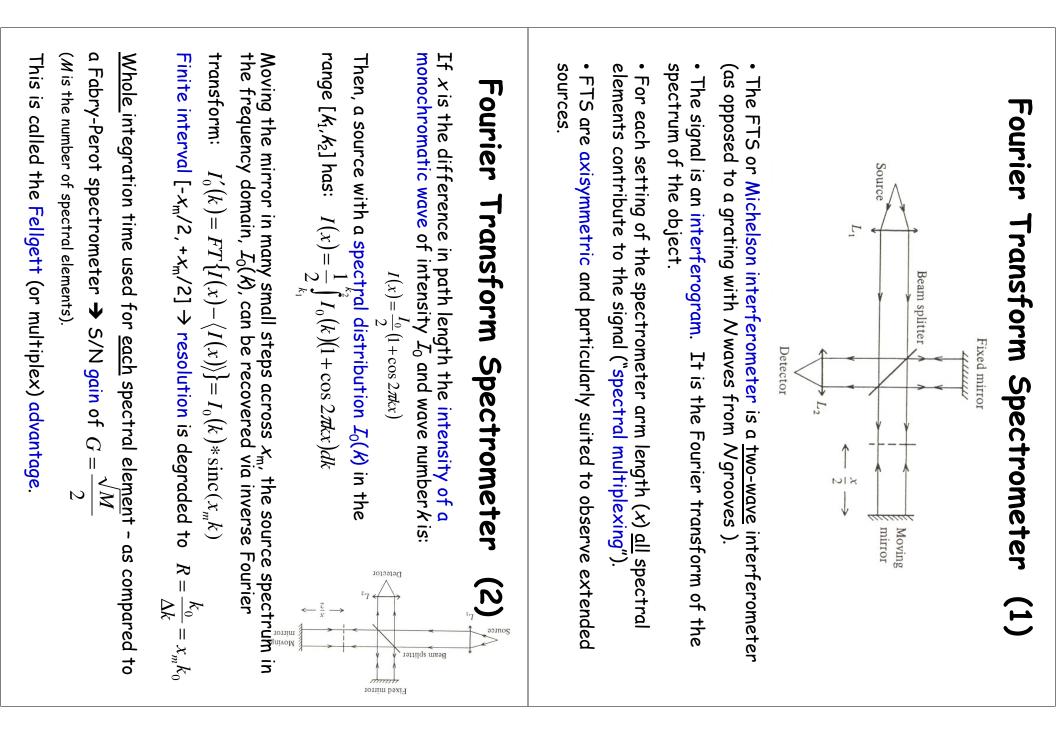
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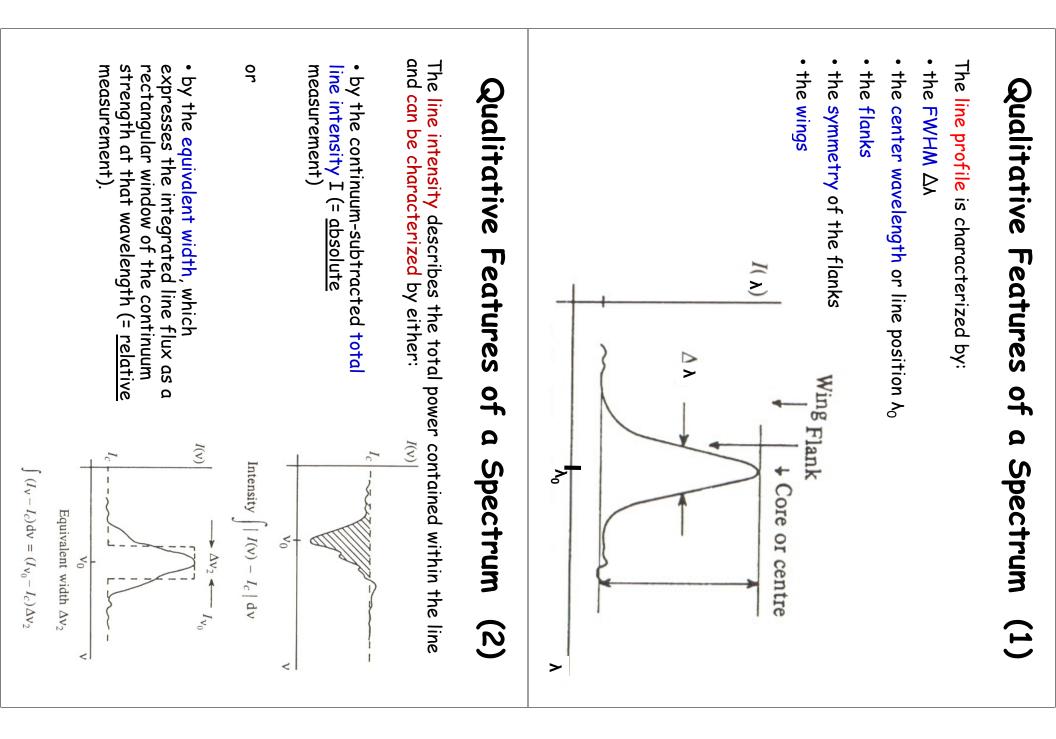
ADVANO







	Fourier- transform (FTS)	Fabry-Perot	Multi-object	Integral field	Echelle	Long-slit	Pros (Spectrometer
SPECTRAL LINE ANALYSIS	 Fellgett advantage: G=√M/2 good for extended sources 	 ideal for large objects high spectral resolution more compact than FTS 	 up to thousands of spectra ideal for spectral surveys 	instantaneous 2D infoideal for resolved objects	high spectral resolutionefficient use of detector	 relatively simple → high throughput easy to calibrate 	Pros and Cons of the Different Types rometer Advantages Disadvantages
	 requires low RN detectors high resolution \(\overline \) wide interval difficult in cryo instruments 	 not practical for large ∆A line and continuum observed at different times → calibration needs pre-disperser 	 complex mechanisms to select fields fibre transmission limits ∆A compact objects/regions only 	 complex optics single objects only 	 challenging grating/optics limited instantaneous ∆A 	 only one object at a time inefficient use of detector space 	Different Types Disadvantages



Measuring Spectral Line Intensity

The most common methods are:

- by numerical integration of the line profile: $\int [I(\nu) I_c] d\nu = f(N)$
- by fitting a Gaussian $\phi_G(\nu) = \frac{1}{\sqrt{2\pi\sigma}} \exp\left[-\frac{(\nu-\nu_0)^2}{2\sigma^2}\right]$ if the line profile is determined by Doppler broadening or the instrumental profile ("unresolved line") [see below].
- by fitting a Lorentzian $\phi_L(\nu) = \frac{1}{2\pi} \frac{\Delta \nu_L}{(\nu \nu_0)^2 + (\Delta \nu_L/2)^2}$ if the line profile is given by collisions, where $\Delta \nu_L = 1/\pi \tau$, with τ the mean time
- between collisions
- by fitting a Voigt profile $\phi_V(v) = \phi_G(v) * \phi_L(v)$ which is a convolution of

Gaussian and Lorentzian profile (= most general case).

Optimal Exraction

detector is non-trivial: Extracting the spectral information from the dispersed light on a real

information should be weighted according to the S/N per pixel: Usually, spectral resolution elements cover more than one pixel o the

$$(\lambda) = rac{\sum_{i} W_i(\lambda) \cdot (C_i(\lambda) - B(\lambda))}{\sum W_i(\lambda)}$$

5

where ${\cal S}$ is the summed signal, ${\cal B}$ is the background, and ${\cal C}$ is the detected signal per pixel *i*.

